



<b>Make</b>	Axcelis
<b>Model</b>	GSD200E2 90KeV
<b>Process</b>	High Current Implanter
<b>Vintage (Year of Manufacture)</b>	W34-2000
<b>Tool Status (Unhooked/Cold shutdown /Warm shutdown/Online)</b>	Unhooked (Warehouse)
<b>Software Version</b>	6.4.4
<b>CIM</b>	Linked

**Hardware Configuration**

<b>Main System</b>	GSD200E2 Implanter	1	✓
<b>SMIF System</b>	Not applicable		
<b>Handler System</b>	Not applicable		
<b>Process Chms</b>	Not applicable		
<b>Others (Pls specify if any)</b>	Not applicable		

**Hardware Configuration (Subfab / Auxilliary Units)**

Cryo compressor	1	✓
Disk Chiller	1	✓

**Missing/Faulty Parts / Accesories below**

Dry pump (RP1 and RP2)	2	
HYT Assy set	1	
P1 Source Turbopump set	1	
Asyst LPT2200 smif	1	

## Configuration

	Axcelis GSD 200E2 Configuration
<b>Vacuum system</b>	
Cryo Compressor	CTI-9650
Beamline Cryo pump 1	OB 8 ( P2 )
Beamline Cryo pump 2	OB 10 ( P3 )
Process cryo P9	N
Source Pump	SCU-1600 (P1) - Non Included
AMU Turbo pump	N
Terminal Rough Pump	Ebara pump 40x20 (RP1) - Non Included
Endstation Rough Pump	Ebara pump 40x20 (RP2) - Non Included
Vacuum controller	HCIG
<b>Endstation Info</b>	
Cassette capability	Four cassette
wafer size	200mm
wafer notch alignment	Automatic Notch alignment capability with buffer cassette
Dummy wafer	Integrated "Dummy Wafer" Fill-In Capability
Wafer handling system	In-Air/In-Vacuum High Throughput Wafer Handling System
Particle Filter system	Class 1, UPLA Filtered Wafer Handling System
Implant angle capability	Two Axis Variable Implant Angle( +/- 11 deg in two axes ) (Quad Implant Capability)
Process disk spindle	GSD series "direct Drive" Process disk ( installed with active cooling and external close loop chiller )
Beam monitoring system	In Situ Beam Potential Monitor
	Real-time patented Dose Control
	Real-Time Beam Profiler( single dimension )
Process Disk	Silicon coated process disk ( UHD large radius fence)
Process disk cooling interlock	Y
Asyst LPT2200 smif Interface capability	Y
<b>Terminal Info</b>	
Gas box Option	Modular gas box
	Four String Gas Box Options
	- 1 High Pressure String
	- 2 SDS string Hydride( Arsine and Phosphine )
	- 2 SDS string Flouride( Boron Trifluoride and germaniumTetrafluoride )
	- 3 Pressure Transducer on SDS string( per string ) -- PSIA
	Mass Flow Controller :
	- 1 kit Unit 1660
	- 4 kits Unit 1662
Extraction PS	0 -90 KV
Extraction voltage monitor	Y
Vaporiser	Y
Ion Source	Eterna ELS( Extended Life Source )
Source bushing	Extended life bushing
	Source liner for Extended life bushing
N2 purge	Bypass Valve and Nitrogen Purge
Extraction Electrode	Extraction Electrode 34

Source injection kit	Y
AMU system	Triple Indexed Mass Analysis Magnet and Power Supply
Post Accel PS	N
Post accel electrode	N
Terminal transformer	Dry transformer
Bias aperture assy	Y
Flag faraday	Y
<b>Charge control Technology</b>	
Secondary Electron Flood Gun	PEF
<b>Closed-Loop Cooling System Selection</b>	
Cooling system	Single loop affinity chiller
<b>General Info</b>	
Control UPS	Y
Main Isolation transformer	Y
Abatement system	EGS237 Novapure - Non Included
Software version	6.4.4
Smoke detector	Y
Exhaust Flow switch	Y
Water leakage sensor	Y
Light Tower	Y
Real Time Particle Detection System	N
Advanced Automation Package	SUN SOLARIS Operator Workstation : Hard Drive, 19" LCD Monitor  SECS I and SECS II Protocols, GEM Interface and Ethernet Ports